

β -Ga₂O₃ NEMS Oscillator for Real-Time Middle Ultraviolet (MUV) Light Detection

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Abstract—We report on the first beta gallium oxide (β -Ga₂O₃) feedback oscillator built by using a β -Ga₂O₃ nanoresonator as the frequency reference for real-time middle ultraviolet (MUV) light detection. We fabricate suspended β -Ga₂O₃ nanodevices through growth of β -Ga₂O₃ nanoflakes using low-pressure chemical vapor deposition (LPCVD), and all-dry transfer of nanoflakes onto microtrenches. Open-loop tests reveal a resonance of the β -Ga₂O₃ nanomechanical resonator at ~ 30 MHz frequency with a quality factor (Q) of ~ 150 – 200 . A closed-loop oscillator is then realized by using a combined optical-electrical feedback circuitry boosting an >70 -fold enhancement to Q , to perform real-time MUV sensing. The oscillator exposed to cyclic MUV irradiation exhibits resonant frequency downshifts, with a responsivity of -3.3 Hz/pW and a minimal detectable power of 0.9 nW, showing great promise of β -Ga₂O₃ transducers for resonant-frequency-based MUV detection.

Index Terms—Beta gallium oxide (β -Ga₂O₃), NEMS, oscillator, ultraviolet light detection.

I. INTRODUCTION

PHOTODETECTION in solar-blind range (<280 nm) has received significant attention thanks to the absence of <280 nm light irradiation in earth atmosphere, providing a “black” background in solar-blind ultraviolet (UV) regime for ultrasensitive and selective illumination detection in missile tracking, fire detection, and environmental monitoring applications [1, 2]. Beta gallium oxide (β -Ga₂O₃), a semiconductor with a monoclinic crystal structure, has an ultrawide bandgap, $E_g \approx 4.5$ – 4.9 eV [3,4,5], perfectly aligned with the cutoff wavelength of the solar-blind range. Various optoelectronic photodetectors (PDs) made of β -Ga₂O₃ crystal have been demonstrated utilizing the ideal bandgap and promising electronic properties of the material [6,7,8]. In addition, owing to its excellent mechanical properties (e.g., measured Young’s modulus, $E_Y = 261$ GPa) [9], β -Ga₂O₃ can be an appealing structural material for building micro/nanoelectromechanical systems (MEMS/NEMS) and new transducers, especially sensors that can capitalize on its ultrawide bandgap embedded in the MEMS/NEMS device platforms. To date, engineering of β -Ga₂O₃ crystal has been mainly focused on electronic devices without any moving parts,

such as field effect transistors (FETs) [10,11,12] and electronic ultraviolet photodetectors [6,7,8]. Transducers exploiting mechanical properties of β -Ga₂O₃ for light sensing are yet to be shown and carefully studied.

In this letter, we describe the construction and measurement of the first self-sustaining β -Ga₂O₃ oscillator by using a β -Ga₂O₃ nanoresonator and a feedback circuitry, for middle UV (MUV, 200–300 nm, strongly overlapped with solar-blind range) light detection and real-time sensing. Fig. 1(a) illustrates the light sensing mechanism of the β -Ga₂O₃ nanomechanical device. The photothermal effect induced by the incident MUV light will elevate the temperature and expand the suspended β -Ga₂O₃ crystal, causing a resonance frequency downshift. By probing the resonance frequency shift of the β -Ga₂O₃ resonator, the intensity of the incident MUV light can be resolved to achieve MUV light detection and real-time sensing.

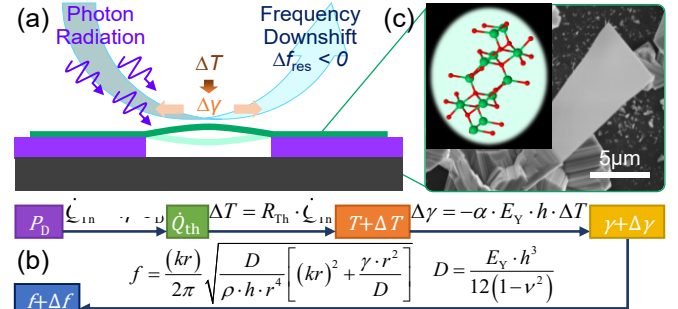


Fig. 1. (a) Transduction scheme of MUV light sensing. (b) Signal transduction chain. P_D : radiation power on device; $\dot{Q}_{th}$: rate of heat flow; T : device temperature; γ : surface tension; E_Y : Young’s modulus of β -Ga₂O₃; h : device thickness; r : device radius; ν : Poisson’s ratio of β -Ga₂O₃; ρ : mass density of β -Ga₂O₃; $(kr)^2$: eigenvalue; f : resonance frequency; (c) A scanning electron microscopy (SEM) image of a β -Ga₂O₃ nanoflake on the growth substrate. Inset: The crystal structure of β -Ga₂O₃.

II. DEVICE FABRICATION

The device fabrication process consists of chemical synthesis and direct transfer of β -Ga₂O₃ nanoflakes for making suspended nanostructures. We perform low-pressure chemical vapor deposition (LPCVD) to grow β -Ga₂O₃ nanoflakes on a 3C-SiC-on-Si substrate. Using high purity Ga pellets and O₂ gas precursor in a 950 °C LPCVD chamber for 1.5 hours, the formation of β -Ga₂O₃ nanostructures proceeds, step by step,

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from β -Ga₂O₃ nanocrystals to nanorods, and then to nanoflakes, without the need of any foreign catalyst [13]. Fig. 1(b) shows an as-grown β -Ga₂O₃ nanoflake on the growth substrate.

We use an all-dry transfer technique to fabricate suspended β -Ga₂O₃ nanomechanical structures (Fig. 2). We secure and harvest the β -Ga₂O₃ nanoflakes from the growth substrate by using a thermal release tape. We apply the harvested β -Ga₂O₃ nanoflakes to a substrate with predefined circular microtrenches. By heating up the substrate to 90 °C and detaching the thermal release tape, the nanoflakes are transferred onto the substrate, thus creating circular β -Ga₂O₃ drumheads on microtrench locations. Fig. 2(b) shows a nanomechanical resonator made of a 73nm-thick β -Ga₂O₃ nanoflake suspended over a $\sim$ 5.2 μ m-diameter circular microtrench. We use this resonator to build the β -Ga₂O₃ oscillator for MUV light detection.

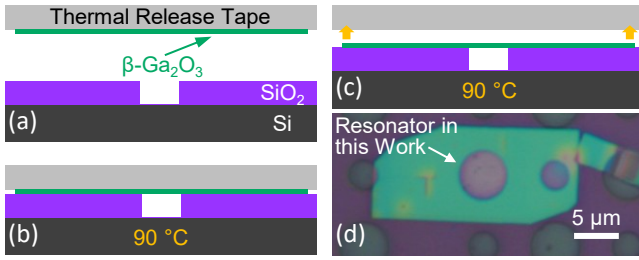


Fig. 2. Fabrication of β -Ga₂O₃ nanomechanical structures. (a) β -Ga₂O₃ nanoflake picked up by thermal release tape. (b) Pressing down the nanoflake and heating the substrate to 90 °C. (c) Lifting the tape in 90 °C temperature, leaving nanoflake on substrate. (d) Image of the fabricated β -Ga₂O₃ device.

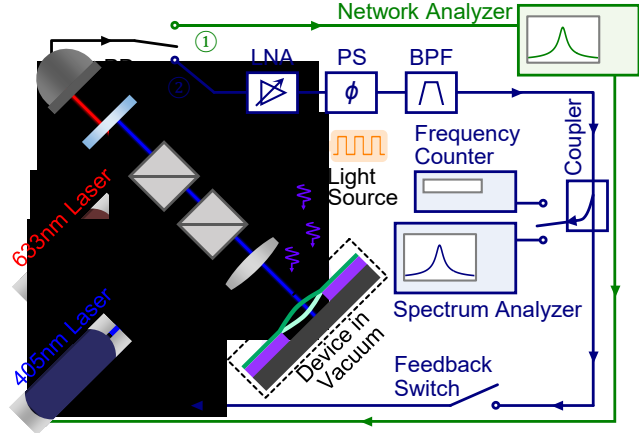


Fig. 3. Schematic of the apparatus for resonance measurement of a β -Ga₂O₃ nanoresonator and the demonstration of MUV detection via a self-sustaining β -Ga₂O₃ oscillator. PD: photodetector; LPF: long-pass filter; BS: beam splitter; LNA: low-noise amplifier; PS: phase shifter; BPF: band-pass filter.

III. RESULTS AND DISCUSSION

Fig. 3 illustrates the system for measuring the resonances of the β -Ga₂O₃ nanomechanical resonator and the self-sustaining β -Ga₂O₃ oscillator for MUV detection. We use a home-built ultrasensitive laser interferometry system [9,14,15] to measure both the undriven thermomechanical noise spectrum and the photothermally driven resonance of the β -Ga₂O₃ nanomechanical resonator in vacuum. We employ a 633nm laser to read out the device motion interferometrically and a 405nm laser to photothermally drive the device. A PD is used to measure the intensity of the device-motion-modulated laser

light. Loop #1 of the system is used for measuring the photothermally driven resonance of the β -Ga₂O₃ nanoresonator. Further, we build a closed-loop oscillator by adding a feedback circuit to the β -Ga₂O₃ resonator (Loop #2 with feedback switched on). The amplitude and phase of the signal from the PD are adjusted by an amplifier and a phase shifter, respectively, to satisfy the Barkhausen criterion for a feedback oscillator. The modified signal is then fed back to the device using the amplitude-modulated 405nm laser. A self-sustaining β -Ga₂O₃ oscillator is therefore achieved without external ac source. For demonstration of MUV light detection using the oscillator, we employ a light source with wavelengths of 200–600 nm to periodically illuminate the resonator. We measure its frequency response using the feedback oscillator.

We first measure the resonance frequency of the β -Ga₂O₃ nanomechanical resonator. Using Loop #1, we measure an open-loop, photothermally driven resonance of the β -Ga₂O₃ resonator at $\sim$ 30 MHz with a quality factor (Q) $\sim$ 150 (Fig. 4(a)). From Loop #2 without feedback, the resonator also exhibits a measured thermomechanical resonance at $\sim$ 30 MHz with a $Q \sim$ 200 (Fig. 4(b)), readout by the spectrum analyzer.

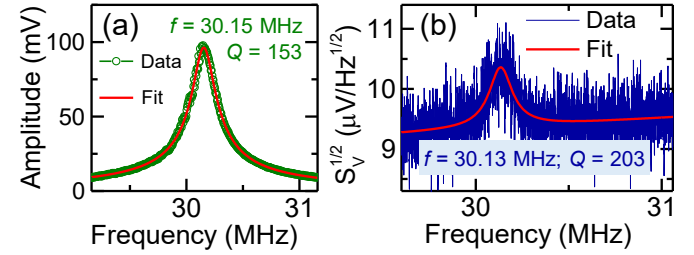


Fig. 4. (a) Photothermally driven response of a circular drumhead β -Ga₂O₃ resonator. (b) Thermomechanical noise spectrum of the resonator.

By closing the feedback switch in Loop #2, an oscillator is built. The Q of the $\sim$ 30MHz resonance is boosted from $\sim$ 200 to an effective $Q_{\text{eff}} > 15,000$ (Fig. 5(a)), which corresponds to a >70 -fold enhancement. Using the frequency counter, we also measure the frequency stability of the oscillator (Fig. 5(b)), which yields an Allan deviation of $\sigma_A(\tau) \sim 10^{-4}$ for $\tau = 0.1$ –10 s.

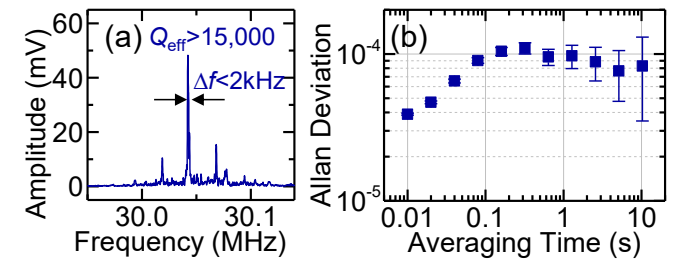


Fig. 5. Performance of the β -Ga₂O₃ feedback oscillator. (a) The closed-loop oscillation spectrum. (b) Measured Allan deviation.

To demonstrate MUV sensing using the β -Ga₂O₃ oscillator, we introduce periodic light irradiation to the device with power intensity adjusted to be $p_s = 1 \text{ W/cm}^2$. Therefore, the incident power of the light on device (P_D) can be calculated using $P_D = A_D \cdot T_{\text{Op}} \cdot (d_s^2/d_c^2) p_s$, where A_D ($\approx 21.2 \mu\text{m}^2$) is the suspended area of the resonator, T_{Op} ($= 0.92$) is the optical transmission coefficient of the fused silica optical window of the vacuum chamber, d_s ($= 5 \text{ mm}$) and d_c ($\approx 10 \text{ mm}$) are the

diameters of the circular MUV light source and the light spot on device substrate, respectively. Thus, an incident power of ~ 24 nW and ~ 49 nW on the circular resonator, for 0.5 W/cm² and 1 W/cm² intensity, respectively, can be calculated. The results of real-time tracking of the oscillator frequency show clear frequency downshifts upon cyclic illumination (Fig. 6). Using $\mathfrak{R} = \Delta f / P_D$, we can get an average responsivity of -3.3 Hz/pW. Given the Allan deviation, the oscillator has a frequency fluctuation of $\delta f = \sigma_A f \approx 3$ kHz at the ~ 30 MHz resonance for $\tau = 0.1$ – 10 s. So we can get a minimal detectable power (MDP) of the oscillator, $\delta P_D = \delta f / \mathfrak{R} \approx 0.9$ nW.

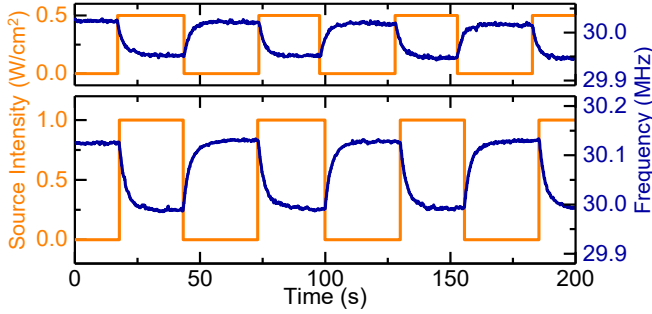


Fig. 6. Responses of the β -Ga₂O₃ oscillator to photon irradiation.

In analysis, β -Ga₂O₃ crystal absorbs photons with wavelengths < 280 nm (because of the 4.5–4.9 eV ultrawide bandgap) and generates heat. The resulting temperature elevation expands the β -Ga₂O₃ device, softens the resonator, and causes resonance frequency downshift. The SiO₂ (with bandgap ~ 9 eV) layer beneath β -Ga₂O₃ has minimal photothermal effect and acts as an isolator of mechanical deformation and a heat barrier between the β -Ga₂O₃ nanoflake and the Si substrate. The photothermal effect in the β -Ga₂O₃ crystal is the main contributor to the observed resonance frequency downshift of the oscillator upon MUV irradiation.

IV. CONCLUSION

We summarize the sensing performance of the β -Ga₂O₃ oscillator and compare it with performance of the β -Ga₂O₃ PDs made in conventional ways (see Table I). With a different photon detection mechanism, the oscillator made by using a β -Ga₂O₃ nanomechanical resonator already show promising performance compared to conventional PDs.

TABLE I
SUMMARY AND COMPARISON FOR MUV SENSING β -Ga₂O₃ OSCILLATOR

Active Area	Responsivity ($\mathfrak{R}$)	Frequency Fluctuation (δf) / Dark Current (I_D)	MDP (δP_D) / NEP ^a	Refs.
$21 \mu\text{m}^2$	-3.3 Hz/pW	~ 3 kHz	0.9 nW	This work
0.8 cm^2	39.3 A/W	$1.1 \mu\text{A}$	1.5×10^{-14} W/Hz ^{1/2}	[6]
$\sim 7 \text{ mm}^2$	0.07 A/W	$\sim 10^{-10}$ A	$\sim 8 \times 10^{-14}$ W/Hz ^{1/2}	[7]
$\sim 0.8 \text{ mm}^2$	8.7 A/W	$\sim 10^{-8}$ A	$\sim 7 \times 10^{-15}$ W/Hz ^{1/2}	[8]

^aNoise equivalent power (NEP) = $(2qI_D)/\mathfrak{R}$, q : electronic charge, I_D : dark current, $\mathfrak{R}$: responsivity.

In conclusion, the demonstration of MUV light detection by

the β -Ga₂O₃ nanostructure-enabled self-sustaining oscillator reveals the potential of using resonant β -Ga₂O₃ nanostructures as ultrasensitive solar-blind UV (< 280 nm) sensing transducers. The demonstrated β -Ga₂O₃ oscillator could pave the way for future solar-blind UV detection using β -Ga₂O₃ nanomechanical transducers for applications including target detection and acquisition, flame detection, and environmental monitoring.

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